

Alexander C Kozen

List of Publications by Year in descending order

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27
papers

1,212
citations

623734

14
h-index

526287

27
g-index

27
all docs

27
docs citations

27
times ranked

2067
citing authors

#	ARTICLE	IF	CITATIONS
1	Atomic Layer Deposition of the Solid Electrolyte LiPON. Chemistry of Materials, 2015, 27, 5324-5331.	6.7	221
2	An all-in-one nanopore battery array. Nature Nanotechnology, 2014, 9, 1031-1039.	31.5	203
3	Stabilization of Lithium Metal Anodes by Hybrid Artificial Solid Electrolyte Interphase. Chemistry of Materials, 2017, 29, 6298-6307.	6.7	155
4	Nanoscale Solid State Batteries Enabled by Thermal Atomic Layer Deposition of a Lithium Polyphosphazene Solid State Electrolyte. Chemistry of Materials, 2017, 29, 3740-3753.	6.7	122
5	Three-Dimensional Solid-State Lithium-Ion Batteries Fabricated by Conformal Vapor-Phase Chemistry. ACS Nano, 2018, 12, 4286-4294.	14.6	96
6	Atomic Layer Deposition and <i>in Situ</i> Characterization of Ultraclean Lithium Oxide and Lithium Hydroxide. Journal of Physical Chemistry C, 2014, 118, 27749-27753.	3.1	69
7	Investigation of the Cathode“Catalyst”Electrolyte Interface in Aprotic LiO ₂ Batteries. Chemistry of Materials, 2015, 27, 5305-5313.	6.7	55
8	ALD Protection of LiMetal Anode Surfaces “Quantifying and Preventing Chemical and Electrochemical Corrosion in Organic Solvent. Advanced Materials Interfaces, 2016, 3, 1600426.	3.7	54
9	Solid Electrolyte Lithium Phosphous Oxynitride as a Protective Nanocladding Layer for 3D High-Capacity Conversion Electrodes. ACS Nano, 2016, 10, 2693-2701.	14.6	48
10	Examining the role of hydrogen in the electrical performance of <i>in situ</i> fabricated metal-insulator-metal trilayers using an atomic layer deposited Al ₂ O ₃ dielectric. Applied Physics Letters, 2013, 102, 173501.	3.3	28
11	Structural Characterization of Atomic Layer Deposited Vanadium Dioxide. Journal of Physical Chemistry C, 2017, 121, 19341-19347.	3.1	25
12	From nanoscience to solutions in electrochemical energy storage. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2013, 31, .	2.1	16
13	Plasma-assisted atomic layer epitaxial growth of aluminum nitride studied with real time grazing angle small angle x-ray scattering. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2017, 35, .	2.1	16
14	In Situ Hydrogen Plasma Exposure for Varying the Stoichiometry of Atomic Layer Deposited Niobium Oxide Films for Use in Neuromorphic Computing Applications. ACS Applied Materials & Interfaces, 2020, 12, 16639-16647.	8.0	16
15	Plasma-enhanced atomic layer deposition of titanium vanadium nitride. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2018, 36, .	2.1	12
16	Improvement of the Electrochemical Performance of LiNi _{0.8} Co _{0.1} Mn _{0.1} O ₂ via Atomic Layer Deposition of Lithium-Rich Zirconium Phosphate Coatings. ACS Applied Materials & Interfaces, 2021, 13, 61733-61741.	8.0	11
17	Effect of varying plasma properties on III-nitride film growth by plasma enhanced atomic layer epitaxy. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2018, 36, .	2.1	10
18	Hot and Cold Pressed LGPS Solid Electrolytes. Journal of the Electrochemical Society, 2021, 168, 010533.	2.9	8

#	ARTICLE	IF	CITATIONS
19	Nanoscale Li, Na, and K ion-conducting polyphosphazenes by atomic layer deposition. Dalton Transactions, 2022, 51, 2068-2082.	3.3	8
20	Influence of temperature on atomic layer epitaxial growth of indium nitride assessed with <i>in situ</i> grazing incidence small-angle x-ray scattering. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, .	2.1	7
21	Plasma-enhanced atomic layer deposition of vanadium nitride. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, .	2.1	6
22	Plasma enhanced atomic layer deposition of titanium nitride-molybdenum nitride solid solutions. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2021, 39, .	2.1	6
23	<i>In situ</i> studies of low temperature atomic level processing of GaN surfaces for atomic layer epitaxial growth. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, .	2.1	5
24	Low temperature surface preparation of GaN substrates for atomic layer epitaxial growth: Assessment of ex situ preparations. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, 020908.	2.1	5
25	Low temperature plasma-enhanced atomic layer deposition of sodium phosphorus oxynitride with tunable nitrogen content. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2022, 40, 032403.	2.1	5
26	Transmission electron microscopy analysis of reduction reactions and phase transformations in Nb ₂ O ₅ films deposited by atomic layer deposition. Journal of Applied Physics, 2021, 129, .	2.5	4
27	Plasma-enhanced atomic layer deposition of titanium molybdenum nitride: Influence of RF bias and substrate structure. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2021, 39, 053408.	2.1	1